

Department of Electrical and Computer Engineering, UC SANTA BARBARA

ECE124A VLSI Principles

Homework #4

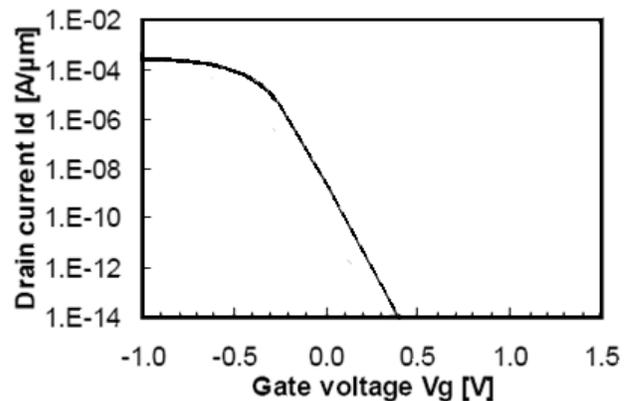
Due Date: Nov. 7 Wed by 5:00pm

For all the questions, the dielectric constant of SiO₂ is $\epsilon/\epsilon_0=3.9$, where $\epsilon_0=8.85 \times 10^{-12} \text{ F m}^{-1}$ is the vacuum dielectric constant. The dielectric constant of Si is $\epsilon_s/\epsilon_0=11.7$.

$e=1.6 \times 10^{-19} \text{ C}$; $kT/e = 26 \text{ mV}$.

Problem 1 MOSFET Threshold Voltage (1)

- For the I_d - V_g curve in the figure below, show linear and velocity saturation regions.
- Find out subthreshold swing. Is this ideal value of sub threshold slope? If yes why? If no, what is ideal value of subthreshold swing?
- If the threshold voltage is defined at a constant current of $10^{-7} \text{ A}/\mu\text{m}$, determine the threshold voltage of the device.
- Read the paper [“Threshold voltage definition and extraction for deep-submicron MOSFETs”](#) by X. Zhou, K. Y. Lim and W. Qian, *Solid State Electronics*, 2001. (On the [course website](#)). If we use the maximum-gm method to define threshold voltage, would the new V_T be higher or lower compared to V_T in 3?
- What are the main reasons for introduction of new threshold voltage definition in short channel devices compared to long channel devices?



Problem 2 MOSFET Threshold Voltage (2)

Consider an aluminum-SiO₂-Si MOSFET structure, where the Si channel is n-type with doping concentration N_D .

The work function difference between aluminum gate and channel is $\Phi_{GC} = -0.35 \text{ V}$.

The oxide thickness is $t_{ox} = 65 \text{ nm}$ and positive (trapped) charges density in oxide is $Q_{ox}/e = 5 \times 10^{10} \text{ cm}^{-2}$.

Design the semiconductor doping concentration N_D to yield a specified threshold voltage $V_{TP} = -1.0 \text{ V}$.

Hint: you need the formula for depletion charge.

Problem 3 MOSFET Substrate Bias Effect

An NMOS device has the following parameters:

N+ poly gate (work function difference between gate and channel is $\Phi_{GC} = -1.06V$);

P-doped channel with doping concentration $N_a=10^{15} \text{ cm}^{-3}$; $n_i=1.5 \times 10^{10} \text{ cm}^{-3}$.

SiO₂ thickness is $t_{ox} = 40\text{nm}$;

Positive charges in oxide: $Q_{ox}=6.48 \times 10^{-9} \text{ C/cm}^2$.

1. Determine V_T .

Hint 1: calculate substrate Fermi potential ϕ_F first.

Hint 2: Inversion layer can be formed even in zero gate voltage due to the positive charges in oxide and the work function difference.

2. Is it possible to apply a V_{SB} voltage such that $V_T=0$? If so, what is the value of V_{SB} ?

Be careful about the sign of ϕ_F .

Problem 4 MOSFET Current Equation

I-V data of a short channel NMOS are measured and listed in the table. Given that the saturation voltage is $V_{DSAT}=0.6V$ and $\beta=\mu C_{ox}W/L= 100\mu\text{A/V}^2$, calculate:

Data	V_{GS} (V)	V_{DS} (V)	V_{BS} (V)	I_D (μA)
1	2.5	1.8	0	1812
2	2.0	1.8	0	1297
3	2.0	2.5	0	1361
4	2.0	1.8	-1.0	1146
5	2.0	1.8	-2.0	1039

1. V_{T0} (threshold voltage with no substrate bias);

2. λ (channel length modulation coefficient)

3. γ (substrate bias coefficient)

4. ϕ_F (substrate Fermi potential)

Problem 5 MOSFET Capacitance

The figure shows the layout of an NMOS transistor with substrate doping $N_a=2 \times 10^{16} \text{ cm}^{-3}$; source/drain doping $N_d=6 \times 10^{19} \text{ cm}^{-3}$; SiO₂ thickness $t_{ox} = 8\text{nm}$; junction depth $X_j=0.4\mu\text{m}$; effective mobility $\mu_n=550 \text{ cm}^2/\text{Vs}$.

Assume gate overlap L_D is 0 and the substrate is grounded ($V_B=0$).

1. What is the maximum drain-to-bulk capacitance C_{DB} ? The drain voltage swings between 0V and 2V.

Hint: $C_{DB} = C_{j0}/(1-V_D/V_0)^m \leq C_{j0}$, where C_{j0} can be calculated using depletion region capacitance formula.

2. Now assume the substrate is biased at -1V, and grading coefficient $m=0.5$.

What is the new maximum C_{DB} ?

